L Number	Hits	Search Text	DB	Time stamp
1	1	kim with dea-yun.in.	USPAT;	2004/07/22 07:58
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
2	5	hwang with jae-won.in.	USPAT;	2004/07/22 08:00
			US-PGPUB;	
			EPO; JPO;	
1			DERWENT	
3	1	kang with eun-ju.in.	USPAT;	2004/07/22 08:00
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
4	7	749112.ap.	USPAT;	2004/07/22 08:06
		·	US-PGPUB;	
			EPO; JPO;	
			DERWENT	
5	3	("5791969"   "6068539"   "6108091").PN.	USPAT	2004/07/22 08:04
6	l 1	6350179.URPN.	USPAT	2004/07/22 08:05
7	512	campbell with william.in.	USPAT;	2004/07/22 08:07
'	0.2	Composit Will William.	US-PGPUB;	2004/01/22 00:01
			EPO; JPO;	
			DERWENT	
8	20	campbell with jarrett with william.in.	USPAT:	2004/07/22 08:07
0	20	Campbell with jarrett with william.in.		2004/07/22 08:07
			US-PGPUB;	
			EPO; JPO;	
40	_	(1150500001   11505505411   11500540011   11500000411   11570004011	DERWENT	0004/07/00 00 40
12	7	("5653622"   "5655951"   "5665199"   "5696601"   "5730642"	USPAT	2004/07/22 08:18
1.0	_	"5827111"   "5865666").PN.		
13	0	6171174.URPN.	USPAT	2004/07/22 08:18
17	4	("5643044"   "5658183"   "5664987"   "6077783").PN.	USPAT	2004/07/22 08:19
18	7	6213848.URPN.	USPAT	2004/07/22 08:19
-	1489	(451/5).CCLS.	USPAT;	2004/07/22 07:58
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	810	(451/8).CCLS.	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	522	(451/57).CCLS.	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	825	(451/65).CCLS.	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
	<b>'</b>		DERWENT	
-	131	((451/5).CCLS.) and endpoint	USPAT;	2004/07/14 14:53
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	127	((451/8).CCLS.) and endpoint	USPAT;	2004/07/14 14:57
1		We are the second secon	US-PGPUB:	
			EPO; JPO;	
			DERWENT	
_	31826	chemical adj mechanical adj polishing	USPAT;	2004/07/14 14:57
	3.025		US-PGPUB;	2007/0//17 17.0/
			EPO; JPO;	
			DERWENT	
_	641	(chemical adj mechanical adj polishing) and endpoint and	USPAT;	2004/07/14 15:03
[ '	071	measur\$3 and control	US-PGPUB;	2004/07/14 10:03
		measuryo anu comuoi		
			EPO; JPO;	]
_	186	((chamical adi machanical adi nalishina) and and naint and	DERWENT	2004/07/44 45:04
-	100	((chemical adj mechanical adj polishing) and endpoint and	USPAT;	2004/07/14 15:04
		measur\$3 and control) and measuring with thickness	US-PGPUB;	
			EPO; JPO;	
L	L		DERWENT	

Search History 7/22/04 8:39:02 AM Page 1
C:\APPS\EAST\Workspaces\10726650.wsp

-	3934	endpoint with detect\$3	USPAT;	2004/07/21 14:30
			US-PGPUB;	
		·	EPO; JPO;	
			DERWENT	
-	556	(endpoint with detect\$3) and thickness with measur\$3	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
	1		DERWENT	
-	156	((endpoint with detect\$3) and thickness with measur\$3) and	USPAT;	2004/07/21 14:32
	<b>i</b>	multiple with layer	US-PGPUB;	•
			EPO; JPO;	
			DERWENT	
-	1492	(451/5).CCLS.	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
_	814	(451/8).CCLS.	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
ļ <b>-</b>	523	(451/57).CCLS.	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	825	(451/65).CCLS.	USPAT;	2004/07/21 15:45
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	216	((451/5).CCLS.) and thickness with measur\$3	USPAT;	2004/07/21 16:14
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	172	((451/8).CCLS.) and thickness with measur\$3	USPAT;	2004/07/21 16:29
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	45	((451/57).CCLS.) and thickness with measur\$3	USPAT;	2004/07/21 16:31
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	20	((451/65).CCLS.) and thickness with measur\$3	USPAT;	2004/07/21 16:33
		·	US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	500	((endpoint with detect\$3) and thickness with measur\$3) and	USPAT;	2004/07/21 16:34
	}	control\$3	US-PGPUB;	
			EPO; JPO;	
			DERWENT	